

[Home](#) | [Login](#) | [Logout](#) | [Access Information](#) | [Alerts](#) |

Welcome United States Patent and Trademark Office

**Search Results****BROWSE****SEARCH****IEEE Xplore Guide**

Results for "(((chip or cell or die) &lt;near/2&gt; (cell or chip or die) &lt;near/2&gt; compar\* and inspect\* ..."

[e-mail](#)

Your search matched 3 of 1373978 documents.

A maximum of 100 results are displayed, 25 to a page, sorted by **Relevance** in **Descending** order.» **Search Options**[View Session History](#)[Modify Search](#)[New Search](#)[Search](#) Check to search only within this results setDisplay Format:  Citation  Citation & Abstract» **Key****IEEE JNL** IEEE Journal or Magazine[view selected items](#) [Select All](#) [Deselect All](#)**IEE JNL** IEE Journal or Magazine**IEEE CNF** IEEE Conference Proceeding 1. **High-sensitivity measurement of particles on SOI wafers**Naruoka, H.; Yoshida, Y.; Iwamatsu, T.; Yamaguchi, Y.; Ipposhi, T.; Yamamoto, S.; [SOI Conference, 1997. Proceedings., 1997 IEEE International](#)

6-9 Oct. 1997 Page(s):182 - 183

Digital Object Identifier 10.1109/SOI.1997.634993

[AbstractPlus](#) | [Full Text: PDF\(272 KB\)](#) [IEEE CNF](#)  
[Rights and Permissions](#)**IEEE STD** IEEE Standard 2. **Recent technology for particle detection on patterned wafers**

Nozoe, M.; Ikota, M.; Motomura, N.;

[Reliability Physics Symposium, 1995. 33rd Annual Proceedings., IEEE International](#)  
4-6 April 1995 Page(s):223 - 227

Digital Object Identifier 10.1109/RELPHY.1995.513683

[AbstractPlus](#) | [Full Text: PDF\(648 KB\)](#) [IEEE CNF](#)  
[Rights and Permissions](#) 3. **Yield enhancement using a memory expert system linked to the wafer ins**

Sugimoto, M.; Hamada, H.;

[Advanced Semiconductor Manufacturing Conference and Workshop, 1995. AS](#)  
[Proceedings. IEEE/SEMI 1995](#)

13-15 Nov. 1995 Page(s):282 - 286

Digital Object Identifier 10.1109/ASMC.1995.484387

[AbstractPlus](#) | [Full Text: PDF\(340 KB\)](#) [IEEE CNF](#)  
[Rights and Permissions](#)[Help](#) [Contact Us](#) [Privacy & :](#)

© Copyright 2006 IEEE -

Indexed by